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**PATENT**

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

**In re Application of:**

Ko et al.

**Serial No.:** Not yet assigned

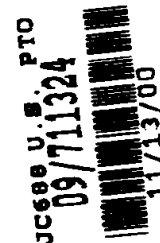
**Filed:** November 13, 2000

**For:** ETCHANT WITH SELECTIVITY FOR  
DOPED SILICON DIOXIDE OVER  
UNDOPED SILICON DIOXIDE AND  
SILICON NITRIDE, PROCESSES WHICH  
EMPLOY THE ETCHANT, AND  
STRUCTURES FORMED THEREBY

**Examiner:** Unknown

**Group Art Unit:** Unknown

**Attorney Docket No.:** 3526.4US  
(97-1136.4)



**NOTICE OF EXPRESS MAILING**

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**INFORMATION DISCLOSURE STATEMENT**

Box PATENT APPLICATION  
Commissioner for Patents  
Washington, D.C. 20231

Sir:

This application is a divisional of application Serial No. 09/625,144, filed July 25, 2000, pending, which is a continuation of application Serial No. 09/102,152, filed June 22, 1998, now U.S. Patent 6,117,791 issued September 12, 2000.

Pursuant to M.P.E.P. 2001.06(b), the Examiner is respectfully requested to consider the information of record in the prior applications, and to confirm in the first Office Action on the

**Attorney Docket No. 3526.4US (97-1136.4)**

merits that such art has in fact been reviewed. A PTO-1449 form listing all of the information of record in the prior applications is enclosed herewith.

This Information Disclosure Statement is filed within three (3) months of the filing date of the above-identified application, and no certification pursuant to 37 C.F.R. § 1.97(c) or a fee pursuant to 37 C.F.R. 1.17(p) is required.

Respectfully submitted,



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BGP/bv:djp

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